Atty. Dkt. No. AMAT/4227.P1/DD/BCVD/.fW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Latchford, et al.

Serial No.: 09/921,938

Filed:

August 02, 2001

Confirmation No.: 8367

For:

Photolithography Scheme Using A Silicon Containing

Resist

Assistant Commissioner for

Patents

Washington, D.C. 20231

Dear Sir:

Group Art Unit: 1756

Examiner:

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The Filing Receipt for the above-referenced application contains an error regarding the attorney docket number. The Filing Receipt recites the attorney docket number as [AMAT/4375/DD/BCVD]. The attorney docket number should read AMAT/4227.P1/DD/BCVD/JW.

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Respectfully submitted,

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PATENT COUNSEL
APPLIED MATERIALS, INC.
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Assignment For Published Patent Application

Applied Materials, Inc.;

Domestic Priority data as claimed by applicant

THIS APPLICATION IS A CIP OF 09/590,322 06/08/2000

Foreign Applications

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Title

Photolithography scheme using a silicon containing resist

Preliminary Class

430

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Team : OIPE

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